

The agreement of Electron Beam - specimen interaction volume between Experimental and Monte Carlo simulation

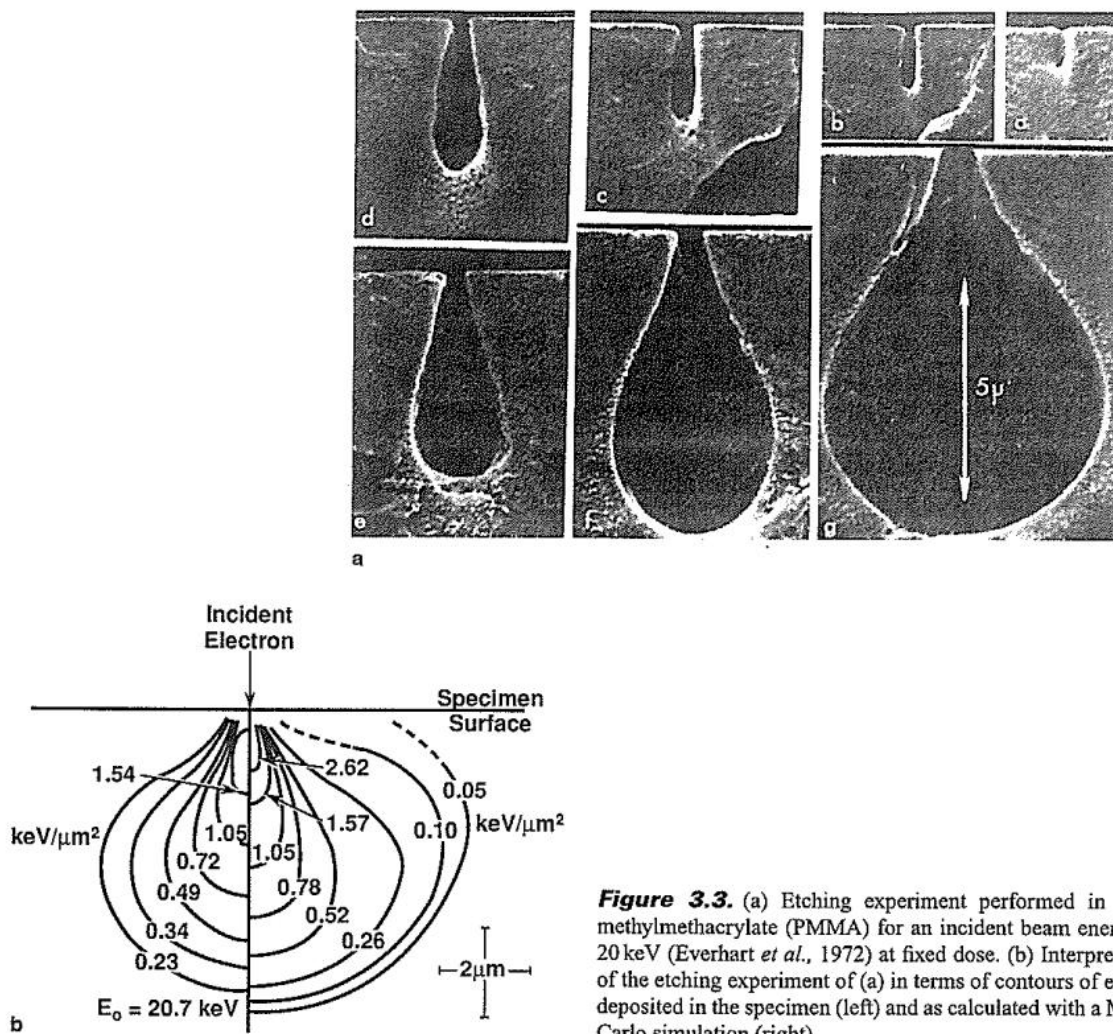


Figure 3.3. (a) Etching experiment performed in polymethylmethacrylate (PMMA) for an incident beam energy of 20 keV (Everhart *et al.*, 1972) at fixed dose. (b) Interpretation of the etching experiment of (a) in terms of contours of energy deposited in the specimen (left) and as calculated with a Monte Carlo simulation (right).